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1A

 ** CONTINUING DATA *****

This application is a DIV of 10/019,700 01/02/2002 PAT 6,818,975
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 ** FOREIGN APPLICATIONS *****

JAPAN 11-189053 07/02/1999

JAPAN 11-293702 10/15/1999

JAPAN 11-308855 10/29/1999

JAPAN 11-323979 11/15/1999

JAPAN 2000-184467 06/20/2000

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35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance				
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000513

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TITLE

Bump forming apparatus for charge appearance semiconductor substrate, charge removal method for charge appearance semiconductor substrate, charge removing unit for charge appearance semiconductor substrate, and charge appearance semiconductor substrate